MD.113.	
Title	Gas and Pressure Sensors
Authors	Lidia Ghimpu
Institution	"D. Ghitu" Institute of Electronic Engineering and Nanotechnologies
Patent no.	Application submitted
Description EN	This invention relates to the manufacture of gas and pressure sensors based on thin oxide layers. The oxide thin layers were obtained by the RF magnetron sputtering method. Carbon substrates and fiber optics were used in the manufacture of these sensors.

Class no. 1

INTERNATIONAL EXHIBITS